

ABSTRACT

Semiconductor manufacturing equipment is provided with a process chamber for depositing a film on a substrate by flowing a gas, a lamp unit arranged in the process chamber to heat the substrate, a first surrounding body which surrounds the lamp unit, a second surrounding body which surrounds the first surrounding body, and a cooling medium communicating apparatus for communicating a cooling medium in a first space between the lamp unit and the first surrounding body and in a second space between the first surrounding body and the second surrounding body.